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DI PADOVA

# Sentaurus Tutorial

MOS capacitor simulation

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## ❑ Sentaurus Structure Editor

- line command: **sde**
- aim: graphical tool to create device geometry and doping profiles (either directly or through process emulation) and set mesh specifications

## ❑ Sentaurus Device

- line command: **sdevice [command\_file\_name]**
- aim: numerical simulation of semiconductor devices
  - numerically solves Poisson and continuity equations on the mesh defined by SDE
  - yields value of electric potential, electron/hole concentration and other physical quantities (electric field, electron/hole current, G/R rate, ...) at any node in the device mesh

## ❑ Sentaurus Visual

- line command: **svisual**
- aim: visualize results derived by Sentaurus Device (and other TCAD tools) in one, two and three dimensions

## ❑ Sentaurus Workbench

- line command: **swb**
- aim: graphical interface that allows to prepare, launch and analyze the results of TCAD Sentaurus simulation tools

# TCAD Sentaurus Online Tutorial

- ❑ Detailed online tutorial on the full TCAD Sentaurus tool suite
- ❑ To open the tutorial
  - launch Sentaurus Workbench  
**swb** &
  - menu Help → Training

# Tutorial #3: MOS capacitor

- ❑ Open a command line terminal, and:

```
cd /nfsd/cadusers/your-username
```

```
mkdir TCAD
```

```
cd TCAD
```

- ❑ Launch firefox (or another web browser), go to the course webpage on eLearning and download the file **tcad-user.sh** into directory TCAD

- ❑ Then, from the terminal, execute the command:

```
source tcad-user.sh
```

- ❑ and launch Sentaurus Workbench:

```
sbw &
```

- ❑ In the left panel of the SWB window you should see a list of folders, the first of which is your working folder:

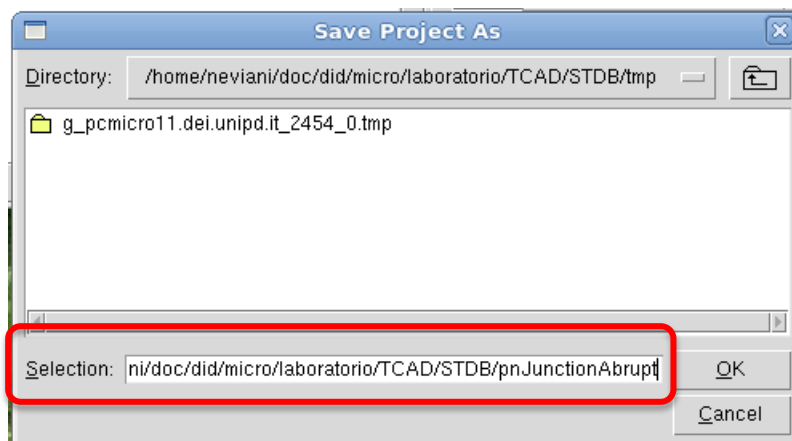
```
/nfsd/cadusers/your-username/TCAD/STDB
```

# Tutorial #3: MOS capacitor

## ❑ Create your first project

- in the upper menu bar, click on **Project → New → New Project**
- then, **Project → Save As → Project ...**
- in the Selection field of the dialog block, write the project save path, then click OK

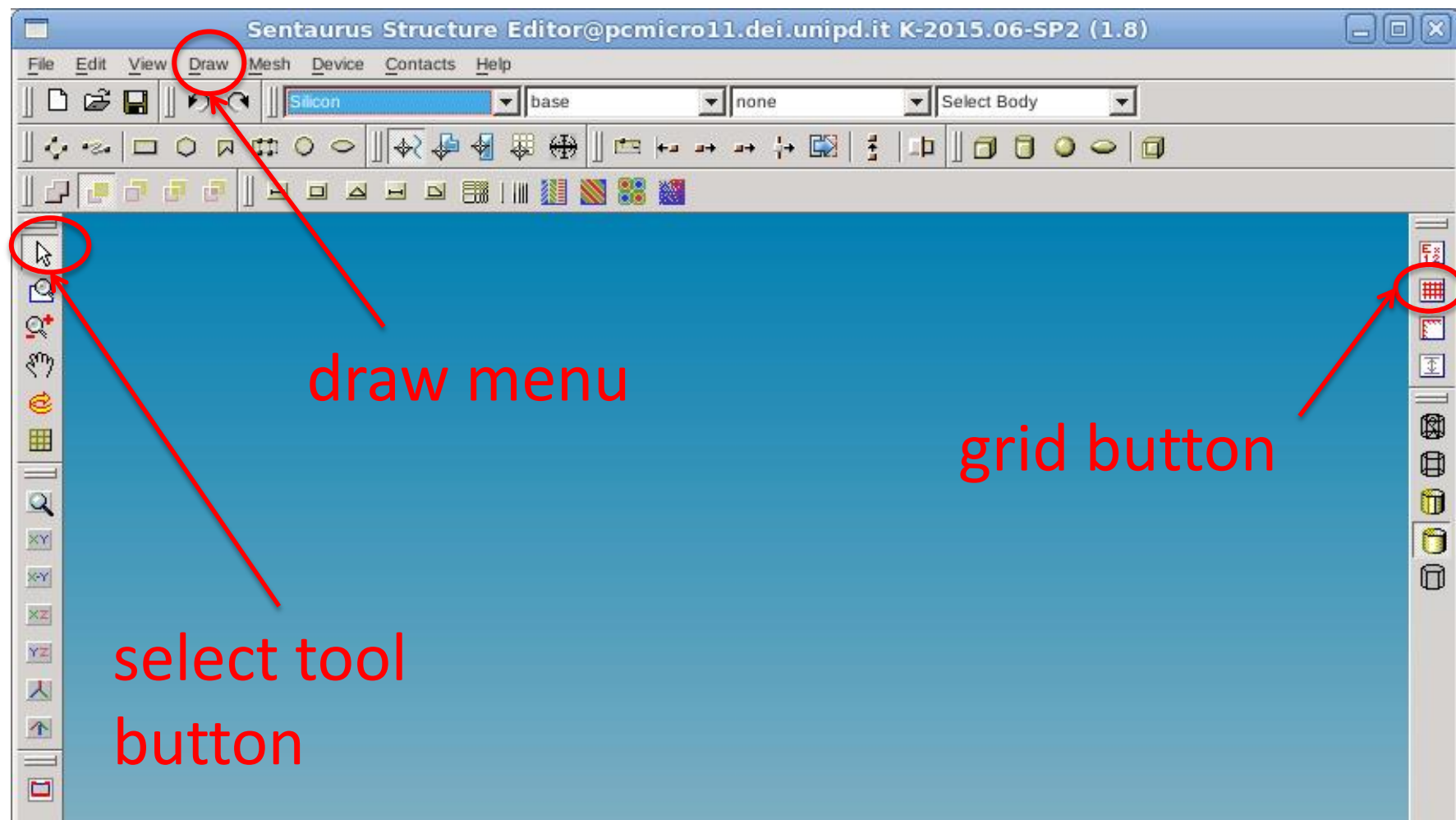
***/nfsd/cadusers/your-username/TCAD/STDB/MOScap***



# Tutorial #3: define device geometry

- ❑ We will now define the device geometry, doping and mesh using SDE
- ❑ Launch SDE from the upper menu bar
  - **Extensions** → **Run Sentaurus Structure Editor**
  - SDE window should appear
- ❑ Prepare SDE for editing
  - choose Select tool on left icon bar (white arrow)
  - click on the grid symbol in the right icon bar, then click Show and Close in the dialog box; a  $1\mu\text{m} \times 1\mu\text{m}$  grid appears in the drawing area
  - in the upper menu bar, click on **Draw**, then **de-select Auto Region Naming** and **select Exact Coordinates**

# Tutorial #3: define device geometry

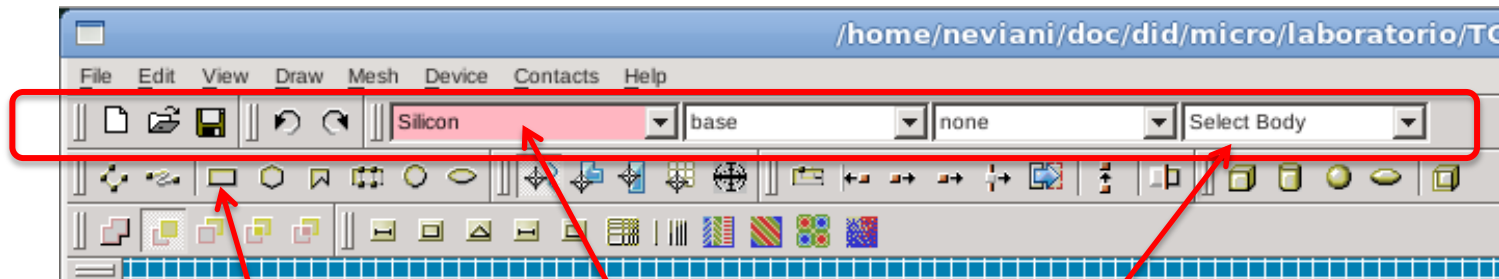




# Tutorial #3: define device geometry

## □ Define the device geometry:

- In the upper icon bar

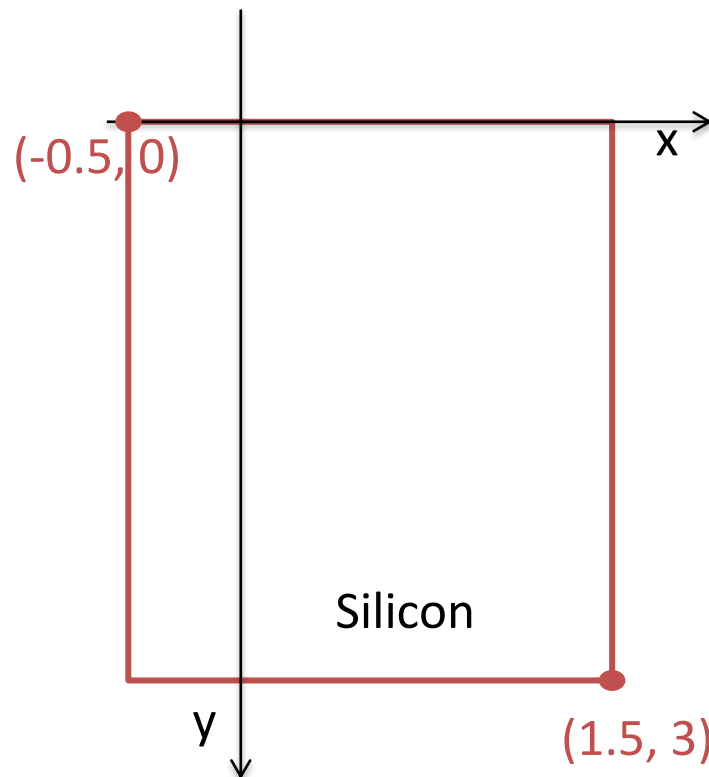


- make sure that **Silicon** is selected in the Material List pull-down menu and that Selection Type is set to **Select Body**
- then, select the **Create Rectangular Sheet Region** icon

# Tutorial #3: define device geometry

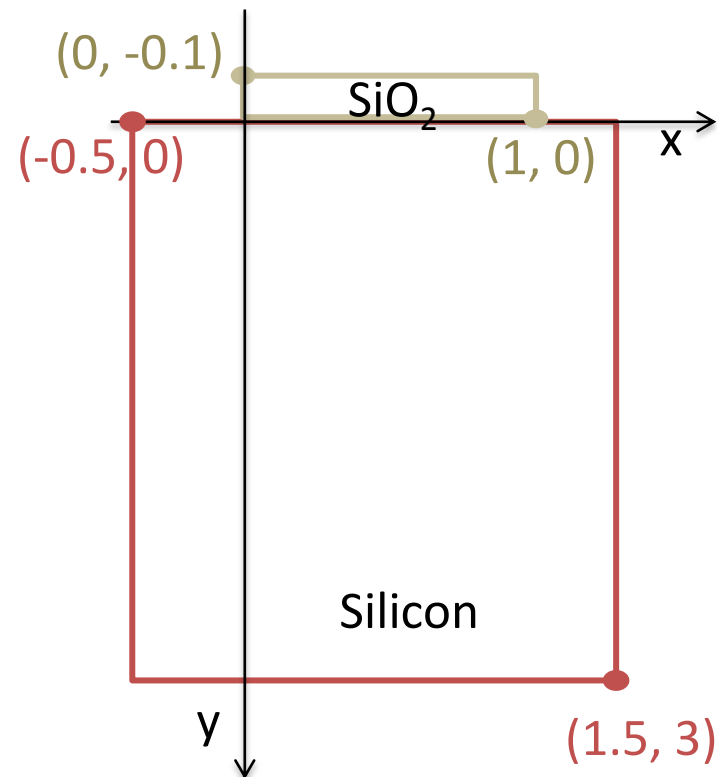
## □ Let us first define the Silicon substrate geometry:

- left-click and drag the mouse to draw a rectangle
- insert the substrate upper left corner and lower right corner coordinates in the Exact Coordinates dialog window, then click OK
  - First Vertex  $(-0.5, 0)$ ; Second Vertex  $(1.5, 3)$
- Enter Region Name (pSub) and click OK



# Tutorial #3: define device geometry

- ❑ Then, define the gate oxide geometry:
  - make sure that  $\text{SiO}_2$  is selected in the Material List pull-down menu
  - as before, left-click and drag the mouse to draw a rectangle and insert the gate oxide region coordinates
    - First Vertex  $(0, -0.1)$ ; Second Vertex  $(1, 0)$
  - Enter Region Name (gateOxide) and click OK
  - Save the model (File → Save Model) with name MOScap



# Tutorial #3: add uniform doping

Constant Profile Placement

Placement Name: ConstantProfilePlacement\_pSub

Placement Type:

- ☐ Ref/ Win
- ☒ Region: pSub
- ☐ Material

Visualization:

Define Ref/Win:

X1: Y1: Z1: Define

X2: Y2: Z2: Apply

Constant Profile Definition:

Name: ConstantProfileDefinition\_pSub

Species: BoronActiveConcentration

Concentration: 1E15

Decay Length: On: NoReplace

Add Placement Delete Placement Close

- ❑ In the upper menu bar, click Device → Constant Profile Placement...
- ❑ Add the suffix pSub to the Placement Name and to the Profile Definition
- ❑ Select Region as profile type and pSub in the pull-down menu
- ❑ Choose Boron Active Concentration as dopant Species and 1E15 as Concentration
- ❑ Finally, click Add Placement and Close

# Tutorial #3: create contacts

- ❑ To complete the device definition, we will now add the gate contact (G) and the substrate ohmic contact (B) on top of the gate oxide and at the bottom of the substrate pSi region, respectively.

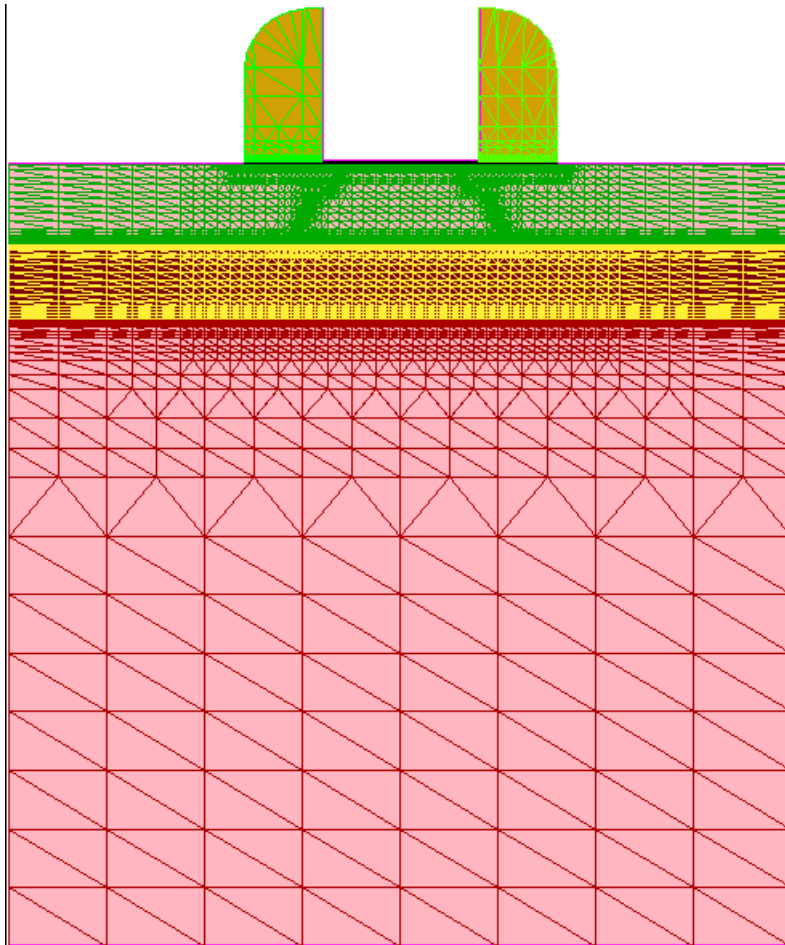
# Tutorial #3: create contacts

- ❑ Contact creation requires two steps
  1. Define the list of contacts of the device
  2. Associate (set) each contact to an edge of the device
- ❑ Define contacts
  - You will now define contacts **G** and **B** of the MOS capacitor
  - Select menu **Contacts** → **Contact Sets**
  - In the dialog box, enter the name of the contact in the **Contact Name** field
  - Click **Set** to add the contact to the **Defined Contact Set**
  - Repeat for each contact, then click Close

# Tutorial #3: create contacts

- ❑ Set contacts on existing edges
  1. You will now associate contacts G and B to the oxide region top edge and to the substrate region bottom edge
  2. Select menu **Contacts** → **Contact Sets**
  3. Select contact G from the Defined Contact Sets
  4. Click Activate and then Close
  5. In the Selection Level list, choose Select Edge
  6. Click the select button (white arrow) on the left panel
  7. Click the top edge of the oxide region; that's where we want to place the gate contact
  8. Select menu **Contacts** → **Set Edges**.
  9. Repeat steps 2 to 8 to place contact B on the bottom edge of the substrate region
- ❑ Save the model

# Tutorial #3: mesh generation



example of device geometry with mesh

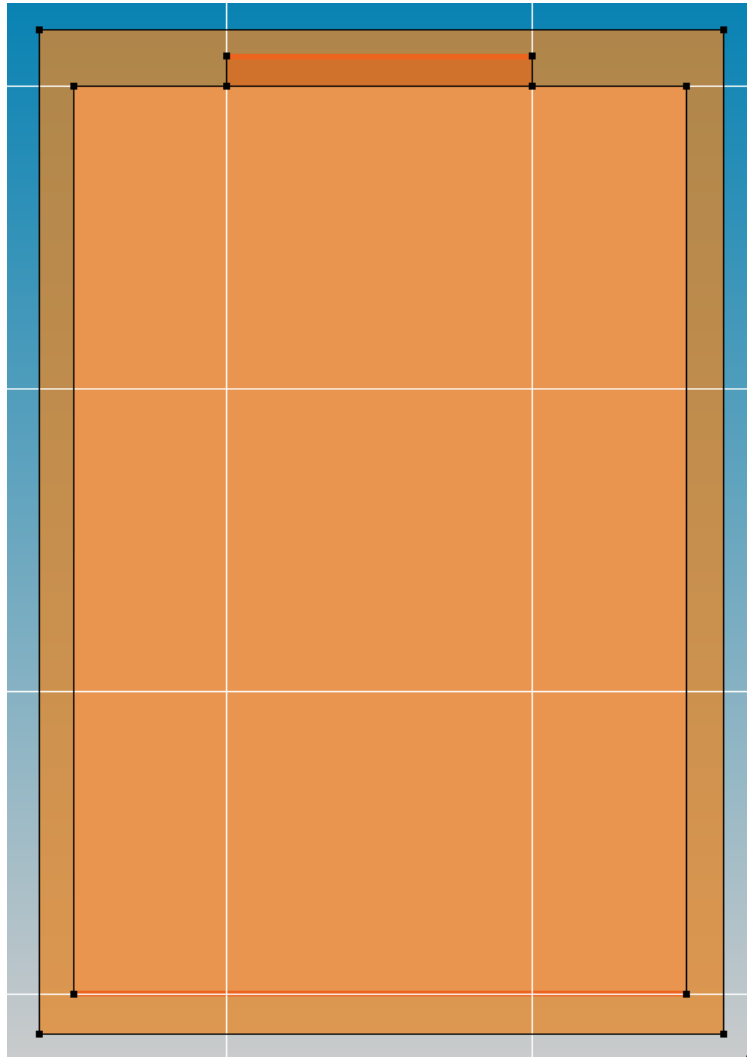
- Numerical simulation tools require the generation of a mesh in order to solve numerically the semiconductor equations
  - a mesh is a graph with nodes and edges that covers the entire device area
  - differential equations are discretized on the mesh nodes becoming algebraic (nonlinear) equations



# Tutorial #3: mesh generation

- ❑ Mesh generation is usually performed in two steps:
  - definition of global mesh settings
  - definition of regional (local) refinements
- ❑ Global mesh setting
  - defines mesh controls that are applied to the entire device structure
  - Select **Mesh** → **Define Ref/Eval Window** → **Rectangle** and draw a rectangle covering the entire device with some margins
  - In the dialog box, do not change the vertex coordinates and insert RefWin.all as Ref/Eval Window Name
  - The global mesh window should appear as shown in the following slide

# Tutorial #3: mesh generation



appearance of MOScap  
device model after  
global mesh definition

# Tutorial #3: mesh generation

- ❑ We will now set the global mesh specifications
- ❑ Select Mesh → Refinement Placement
- ❑ In the Refinement Specification dialog box (see next slide):
  1. change Placement Name to RP\_RefWin.all
  2. select RefWin.all in the Ref/Eval Window panel (this identifies the area where refinement specifications will be applied)
  3. select pSub and gateOxide in the Region panel
  4. change the Refinement Definition Name to RD\_RefWin.all
  5. insert 0.1 in the Max/Min Element Size fields (X and Y directions only)
  6. click on More, then, as Refinement Function, choose Interface Length, select pSub and gateOxide from the pull-down menus, insert 0.01 and 1.5 as (sensitivity) Value and Factor, respectively, then click Add
  7. finally, click on Create Refinement and Close
  8. Save the model

# Tutorial #3: mesh generation

refinement specifications for the global mesh

The screenshot shows the 'Refinement Specification' dialog box with the following components and annotations:

- 1.** Placement Name: RP\_RefWin.all
- 2.** Placement Type: RefWin.all
- 3.** Regions: pSub, gateOxide
- 4.** Refinement Definition Name: RD\_RefWin.all
- 5.** Max Element Size: 0.1 (X and Y directions)
- 6.** Refinement Functions: Value Difference (pSub, Value: 0.01), Gradient (gateOxide, Factor: 1.5), Interface Length (checked). DoubleSide and UseRegionNames are also checked.
- 7.** Create Refinement button

Buttons: Create, Modify, Add, Delete, Close.

Function / Interface	Criteria	Value	Factor	DoubleSide	UseRegionNames
"pSub" "gateOxide"	Interf...	0.01	1.5	"DoubleSi...	"UseRegionNames"

# Tutorial #3: mesh generation

- ❑ We will now define the regional refinements
  - the area immediately below the Si/SiO<sub>2</sub> interface requires a finer mesh due to the expected strong gradients of main physical quantities in the space charge region (carrier concentration, electric field, ...)
  - to this aim, we shall first define a refinement window below the Si/SiO<sub>2</sub> interface and then set new refinement specifications to that region
  - Select Mesh → Define Ref/Eval Window → Rectangle and draw a rectangle approximately below the interface
  - In the dialog box, insert the following coordinates
    - First Vertex                      X: -0.1    Y: 0
    - Second Vertex                  X: 1.1     Y: 1
    - Ref/Eval Window Name        RefWin.Channel

# Tutorial #3: mesh generation

- ❑ Now let's set the mesh specification in the RefWin.Channel window
- ❑ Select Mesh → Refinement Placement
- ❑ In the Refinement Specification dialog box:
  - change Placement Name to RP\_RefWin.Channel
  - select RefWin.junction in the Ref/Eval Window panel
  - change the Refinement Definition Name to RD\_RefWin.Channel
  - insert 0.1 and 0.05 in the Max/Min Element Size fields for the X direction, 0.05 and 0.01 for the Y direction
  - finally, click on Create Refinement and Close
  - Save the model

# Tutorial #3: mesh generation

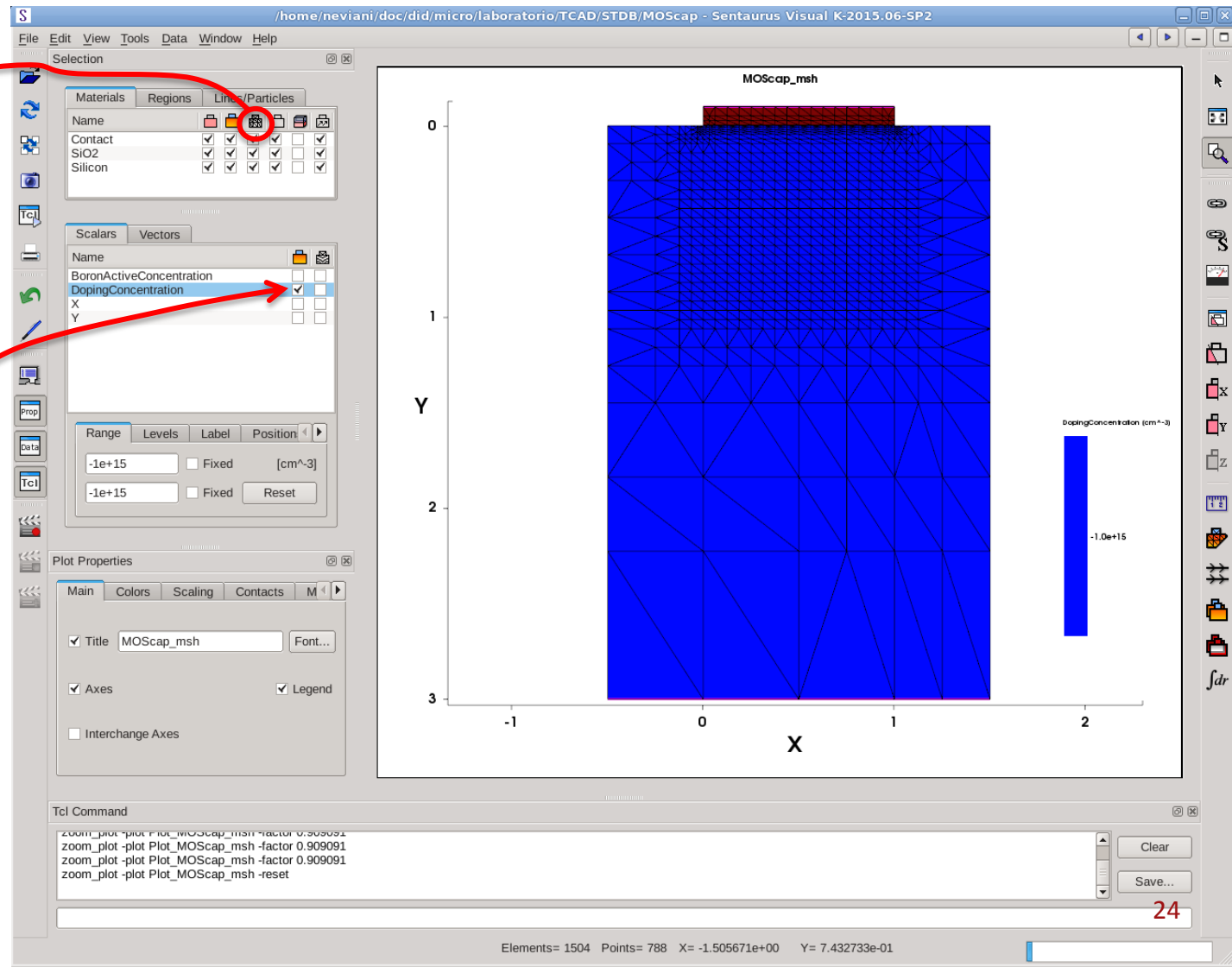
- ❑ We finally generate the mesh
  - Select Mesh → Build Mesh
  - In the dialog box, make sure that the file full path in the Save Grid to File field is correct  
(/nfsd/cadusers/your-username/TCAD/STDB/MOScap/MOScap)
  - Select SVisual as Mesh Viewer, then click Build Mesh
  - After mesh generation is completed, SVisual (the plotting tool for visualizing TCAD data) opens, showing the device structure and mesh (see next page)



# Tutorial #3: mesh generation

click the Mesh icon to show the device mesh

check the Doping Concentration box to show active doping density





# Tutorial #3: device simulation

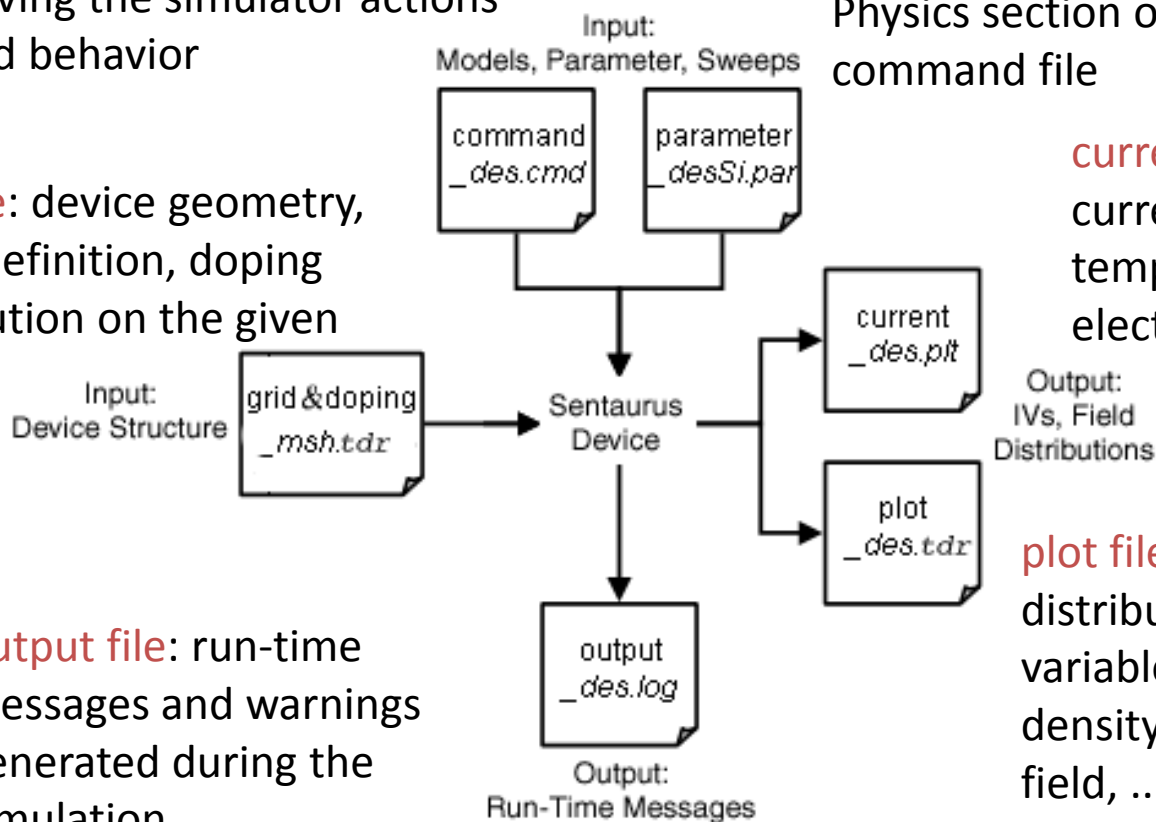
- ❑ We'll now use **Sentaurus Device** to run a series of drift-diffusion simulations of the MOS capacitor
- ❑ We'll use the SWB interface to setup and execute the simulation
- ❑ Sentaurus Device actions and behavior are driven by statements contained in the command file
- ❑ The command file contains six sections:
  - File → input and output files
  - Electrode → contact types and boundary conditions (V, I)
  - Physics → physical models used in the simulation
  - Plot → variables to be saved in the plot file
  - Math → numerical simulation parameter
  - Solve → simulation commands

# Tutorial #3: device simulation

**command file:** statements driving the simulator actions and behavior

**parameter file:** parameters of physical models defined in the Physics section of the command file

**grid file:** device geometry, mesh definition, doping distribution on the given mesh



**current file:** voltages, currents, charges, temperature at device electrodes

**plot file:** spatially distributed solution variables (electron/hole density, potential, electric field, ...) and their derivatives

**output file:** run-time messages and warnings generated during the simulation

# Tutorial #3: device simulation

## ❑ In the SWB window

- right-click on the header **No Tools** of the spreadsheet leftmost column and then click on Add... (see next page)
- then, in the dialog box, click on Tools..., then, in the Select DB Tool window, click SDEVICE, then OK, and again OK
- the SDEVICE icon now appears on the header of the leftmost column

# Tutorial #3: device simulation

The screenshot shows the Synopsys TCAD interface in Runtime Mode. The main window displays a project tree on the left and a central workspace. A red box highlights the 'No Tools' button in the 'Add Tool' dialog, with a red arrow pointing to the 'Tools...' button in the 'Add Tool' dialog. Another red arrow points from the 'Tools...' button to the 'SDEVICE' tool in the 'Select DB Tool' panel.

**Select DB Tool**

SENTAURUS PROCESS SIMULATION, STRUCTURE GENERATION, INTERCONNECT SIMULATION, LITHOGRAPHY

SPROCESS SPTOP3D SPTOPD SDE SINTERCO SLITHO

SENTAURUS GRID GENERATION

SNMESH

SENTAURUS DEVICE SIMULATION

SDEVICE EMW SBAND

SENTAURUS VISUALIZATION

SVISUAL INSPECT

EXTRACTION

RAPHAEL

UTILITIES

TDX SHELL TCLSH MY TOOL

TAURUS PROCESS AND DEVICE SIMULATION

# Tutorial #3: device simulation

## ❑ Command file creation

1. Right-click on the SDEVICE icon, then Edit Input → Commands...
2. An empty file opens; the file name is `sdevice_des.cmd` and it is located in the MOScap working directory
3. In the web browser, open the course webpage on eLearning and download the file `command_file1.txt` into directory TCAD
4. Open the file, select all the file content, then copy and paste the content in the `sdevice_des.cmd` empty file
5. Save the file; before exiting, we'll take a closer look to the file content

# Tutorial #3: device simulation

```
File {
    Grid="MOScap_msh.tdr"
    Plot="@tdrdat@"
    Current="@plot@"
    Output="@log@"
}
Electrode {
    {name="G" voltage=-1.0
      barrier=-0.51}
    {name="B" voltage=0.0}
}
Physics {
    Mobility( DopingDep
      HighFieldSaturation Enormal )
    EffectiveIntrinsicDensity(
      OldSlotboom )
    Recombination( SRH(DopingDep) )
}
```

## File section:

- name of file containing device geometry, doping and grid
- output files names based on simulation node

## Electrode section:

- definition of electrode type, features and boundary condition (V or I)

## Physics section:

- declaration of physical models to be used in the simulation

# Tutorial #3: device simulation

```
Plot { eDensity hDensity
      eCurrent hCurrent
      ...
}
Math {
      ...
}
Solve {
  Coupled ( Iterations= 150){
    Poisson }
  Coupled { Poisson Electron
    Hole }
* Gate voltage sweep
  Quasistationary(InitialStep=0.01
    MinStep= 1e-5 MaxStep= 0.2
    Goal{Name="G" Voltage=@VGB@})
    {Coupled {Poisson Electron
      Hole } } }
```

## Plot section:

- internal variables to be saved

## Math section:

- simulator numerical solver parameters

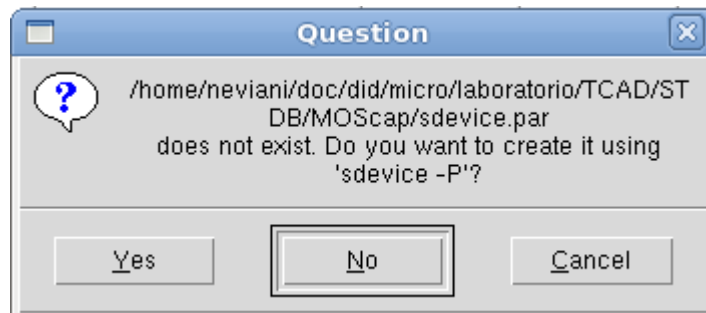
## Solve section:

- sequence of simulation commands activated sequentially

# Tutorial #3: device simulation

## ❑ Parameter file

- Optional file used to specify parameters of physical models different from the default values
- Not needed when the device regions are made with standard materials contained in SDE material list
- Right-click on the SDEVICE icon, then Edit Input → Parameters...



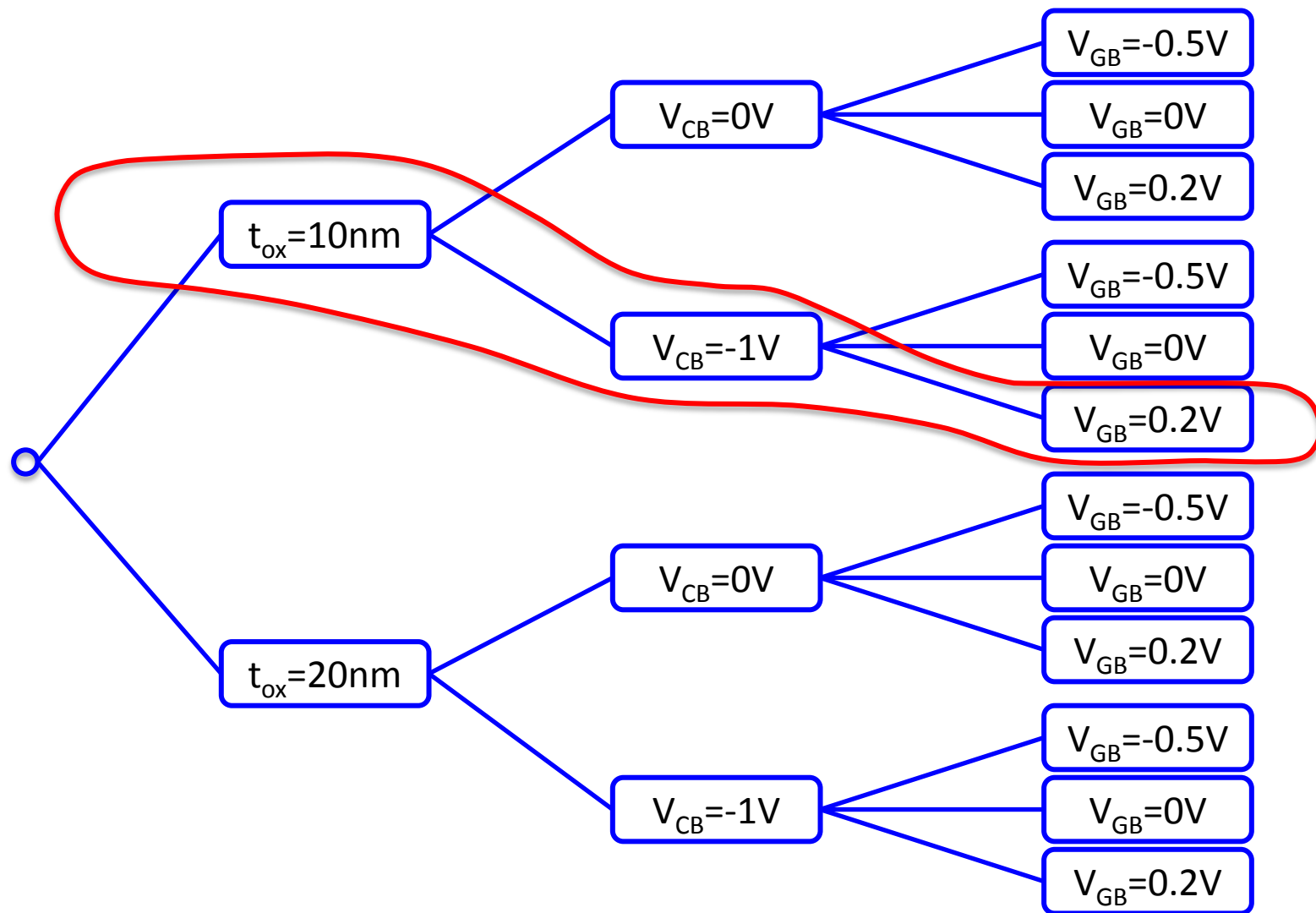
- left-click on No
- an empty file opens; save the empty file and exit



# Tutorial #3: device simulation

- ❑ Device simulators are normally used to execute a set of experiments (simulations) where one or more parameters are changed
- ❑ The simplest example is when a series of voltage values are applied to a terminal
  - one dc simulation per voltage value is executed
- ❑ In general, multiple parameters are changed, originating a graph tree where each root-leaf path corresponds to a combination of parameters values
  - Example: three-terminal MOS capacitor where  $t_{ox}$ ,  $V_{GB}$  and  $V_{CB}$  are changed

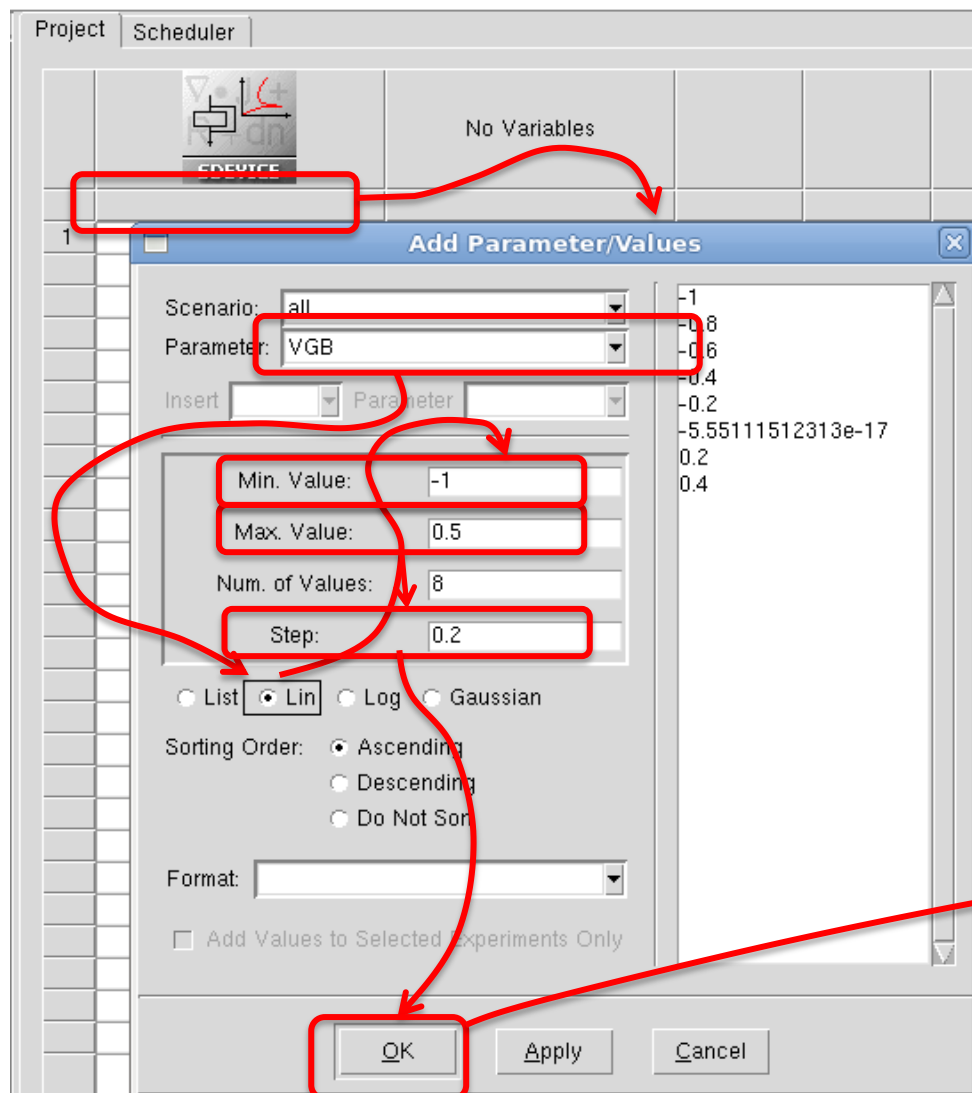
# Tutorial #3: device simulation



# Tutorial #3: device simulation

- ❑ We'll define a simple set of experiments where  $V_{GB}$  is varied to take on the values listed below:
  - $V_{GB} = \{-1, -0.8, -0.6, -0.4, -0.2, 0, 0.2, 0.4\} V$
- ❑ In SWB window, right-click on the cell below the SDEVICE icon, then left-click on Add Parameter/Value
- ❑ Write VGB in Parameter field
- ❑ Select the Lin button, to insert the list of VGB values as a linearly-spaced sequence
- ❑ Write -1 as Min Value, 0.5 as Max Value, and 0.2 as Step, then click OK

# Tutorial #3: device simulation



Project Scheduler

SDEVICE

	SDEVICE	VGB
1	[n12]: --	[n11]: -1
2		[n13]: -0.8
3		[n14]: -0.6
4		[n15]: -0.4
5		[n16]: -0.2
6		[n18]: 0.2
7		[n19]: 0.4
8		

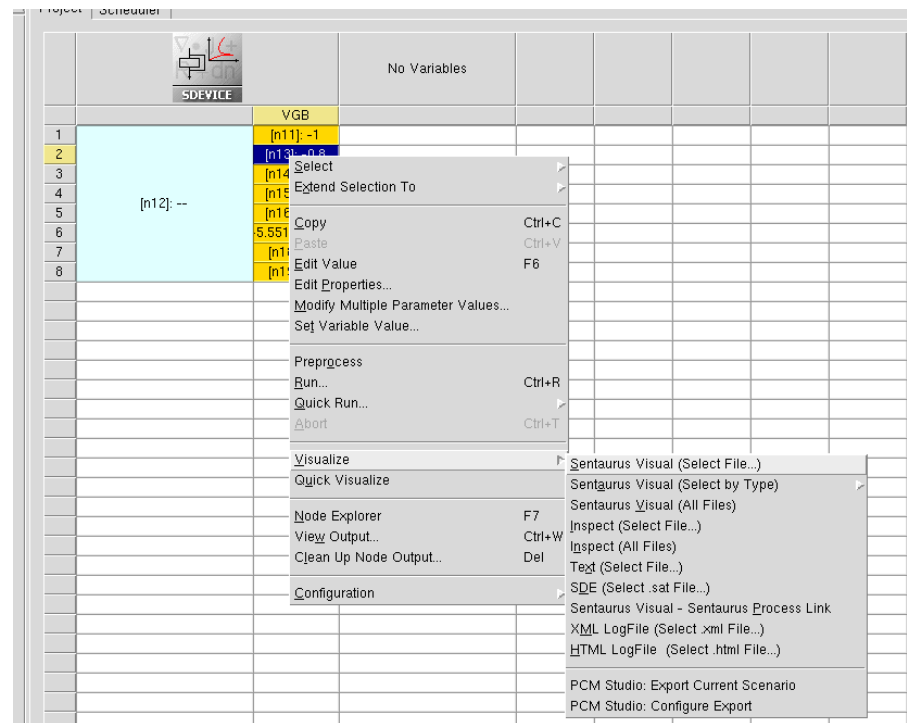
# Tutorial #3: device simulation

- ❑ To execute a dc drift-diffusion simulation of the MOS capacitor in each of the seven nodes defined before:
  - select the nodes (click on the first node, then Shift+click to add the remaining nodes)
  - right-click on anyone of the selected nodes
  - click **Run**; if asked to, save the project; then, make sure **Preprocess, then run** button is selected and click OK
  - after a few seconds, the Project Log window opens showing messages regarding the simulations being run
  - as the simulations progress, the node cell color changes according to the simulation status
  - when all node cells are yellow, the simulations are successfully completed

# Tutorial #3: post-processing

Simulation results can be analyzed with the help of SVISUAL

- Right-click the node corresponding to VGB=-0-8V → Visualize → Sentaurus Visual (Select File...)
- A dialog box with two files opens:
  - n13\_des.plt
  - n13\_des.tdr
- Note that the node number might be different
- Select the file with tdr extension and click OK
- Sentaurus Visual window should open





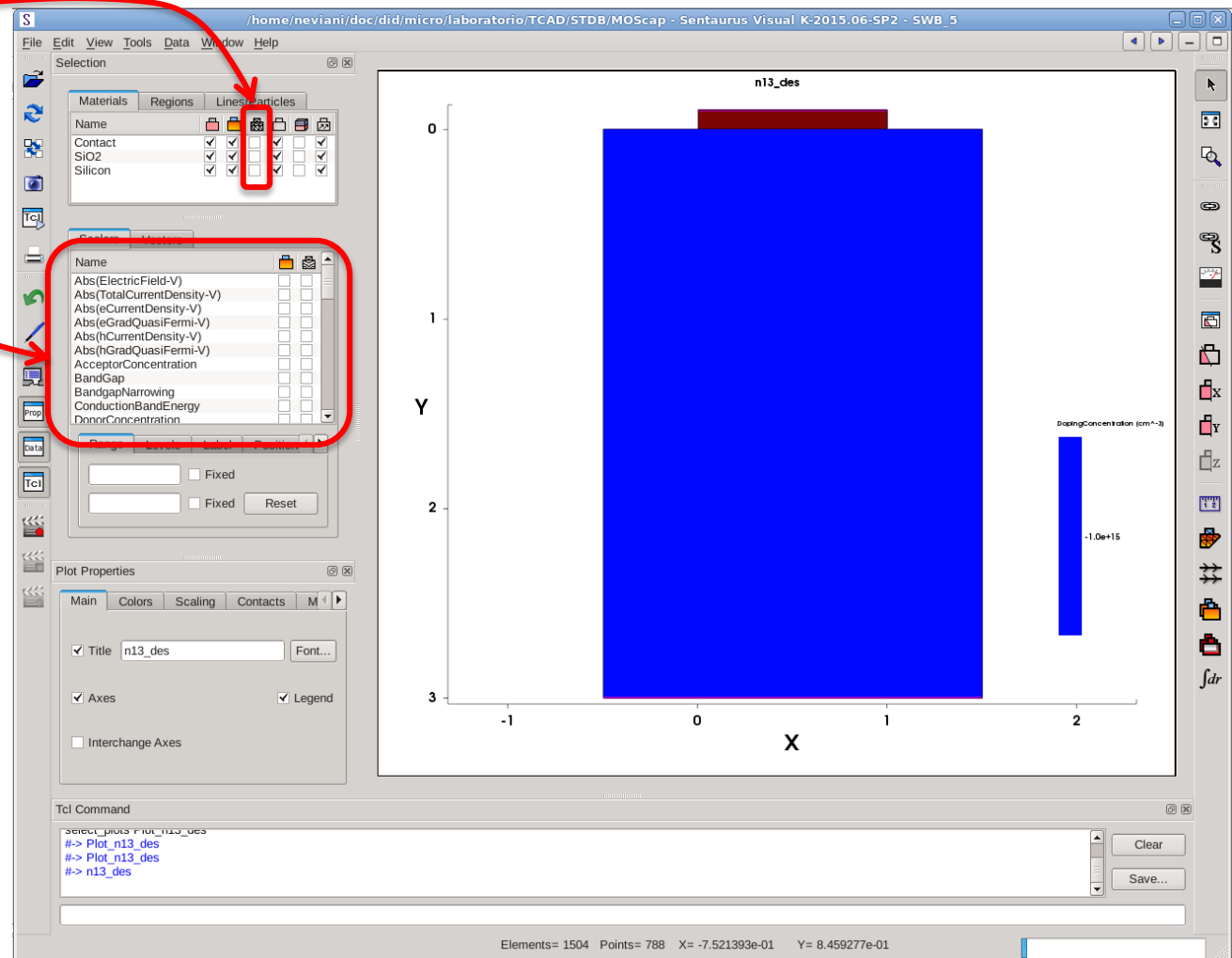
# Tutorial #3: post-processing

## □ Sentaurus Visual window

activate grid  
visualization

select physical  
quantity to visualize  
(default: doping  
concentration)

try to visualize:  
ElectrostaticPotential  
eDensity  
hDensity



# Tutorial #3: ac simulation

- ❑ In single-device physical simulation, Sentaurus Device solves the Poisson and Continuity equation using the drift-diffusion transport model on a 2D or 3D portion of the device geometry
- ❑ In mixed-mode simulation, the device to be physically simulated is included in a circuit with ideal lumped components (resistors, capacitors, inductors, voltage/current generators) and active components with compact electrical models (transistors, diodes)
- ❑ Simulation of the ac response of a physical device is a special case of mixed-mode simulation



# Tutorial #3: ac simulation

- ❑ In its simplest form, small-signal ac simulation requires voltage (or current) dc and ac signal generators and the device to be physically simulated
- ❑ The Solve section of the command file contains statements to:
  - solve the device equation at equilibrium
  - bring the device dc voltages to the initial value
  - ramp the device dc voltage from the initial to the final value
  - inside the ramp statement, an ac solution statement to find the small-signal ac response of the device for every dc voltage defined in the ramp

# Tutorial #3: ac simulation

- ❑ In order to run a small-signal ac simulation we need to change the command file:
  - adding a **Device** section for each device to be physically simulated
  - adding a **System** section that defines the mixed-mode circuit
  - change the **Solve** section to define a step-by-step variation of a dc voltage/current and a linearized ac analysis to be performed in a subset of dc points

# Tutorial #3: ac simulation

- ❑ In the SWB window, right-click on the SDEVICE icon → Edit Input → Commands...
- ❑ The sdevice\_des-cmd command file opens; click on File → Save As... and save the file with a new name (e.g. MOScap\_ac.cmd)
- ❑ Select and delete the content of the file
- ❑ Download command\_file2.txt from the eLearning website and copy its content into MOScap\_ac.cmd file
- ❑ Save the file and before exiting take a closer look to the Device nMOScap section and the System section

# Tutorial #3: ac simulation

```
Device nMOScap {
  Electrode {
    {name="G" voltage=0.0
barrier=-0.51}
    {name="B" voltage=0.0}  }
  File {
    Grid="MOScap_msh.tdr"
    Plot="@tdrdat@"
    Current="@plot@"  }
  Physics {
    Mobility( DopingDep
      HighFieldSaturation Enormal)
    EffectiveIntrinsicDensity(
      OldSlotboom )
    Recombination (SRH (DopingDep) )
  } }
```

## Device section:

- needed for every device to be physically simulated
- includes an Electrode, a File and a Physics section that define the properties of the device
- a unique device name (nMOScap in this example) identifies the device model

# Tutorial #3: ac simulation

```
System {  
    nMOScap C1 (G=g B=b)  
    Vsource_pset vg ( g 0 ) { dc = 0}  
    Vsource_pset vb ( b 0 ) { dc = 0}  
}
```

## System section:

- defines the netlist of the circuit to be simulated
- in this example, the terminals G and B of nMOScap device defined in the Device section with the same name are connected to the circuit nodes g and b
- a voltage generator vg is connected between node g and ground (node 0)
- a second voltage generator is connected between node b and ground

# Tutorial #3: ac simulation

```
Solve {
  NewCurrentPrefix="init"
  Coupled(Iterations=150) {Poisson}
  Coupled{Poisson Electron Hole}

  Quasistationary (
    InitialStep=0.1 Increment=1.3
    MaxStep=0.5 Minstep=1.e-5
    Goal { Parameter=vg.dc
          Voltage=-2.5}
    ){ Coupled { Poisson Electron
Hole } }
  ...
}
```

## Solve section:

- initial solution with boundary conditions specified in the Electrode and in the System sections
- second simulation step to bring the vg voltage source dc voltage to -2.5 V

# Tutorial #3: ac simulation

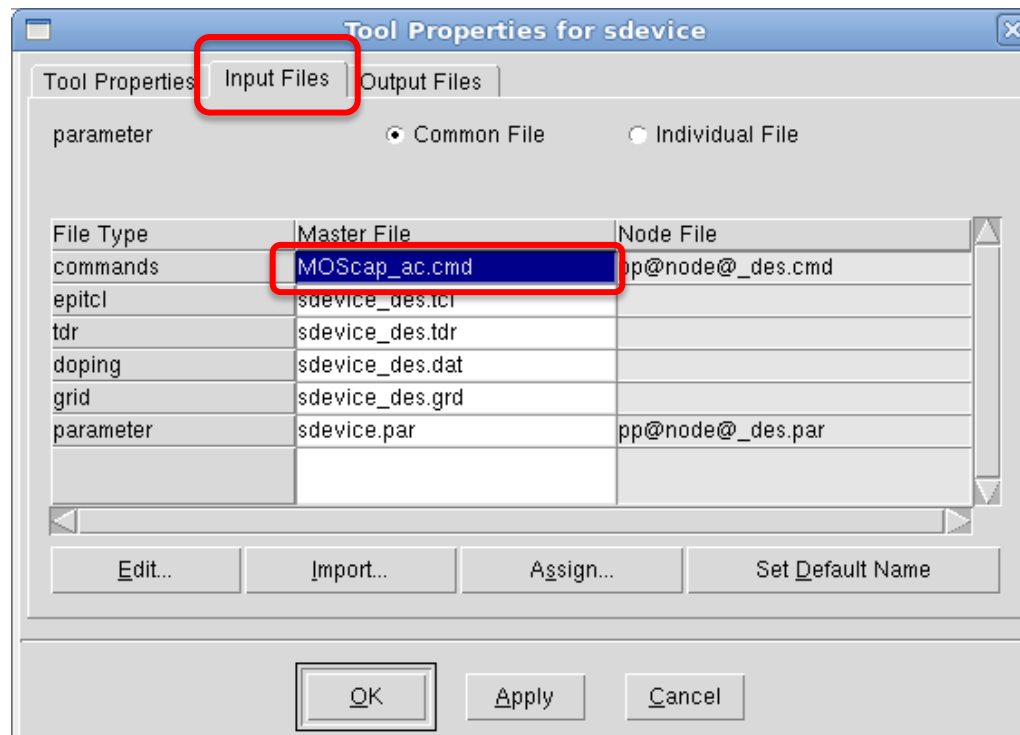
```
Solve {
  ...
  #-ramp gate
  NewCurrentPrefix=""
  Quasistationary (
    InitialStep=0.01 Increment=1.3
    MaxStep=0.05 Minstep=1.e-5
    Goal { Parameter=vg.dc
          Voltage=2.5})
  { ACCoupled (
    StartFrequency=1e3
  EndFrequency=1e3 NumberOfPoints=1
  Decade
    Node(g b) Exclude(vg vb)
    ACCompute (Time = (Range =
(0 1) Intervals = 20))
    ){ Poisson Electron Hole }
  } }
```

## System section:

- dc voltage of vg generator is ramped from the value reached in the previous step (-2.5V) to 2.5V
- a small-signal ac analysis is coupled with the quasi-stationary dc ramp

# Tutorial #3: ac simulation

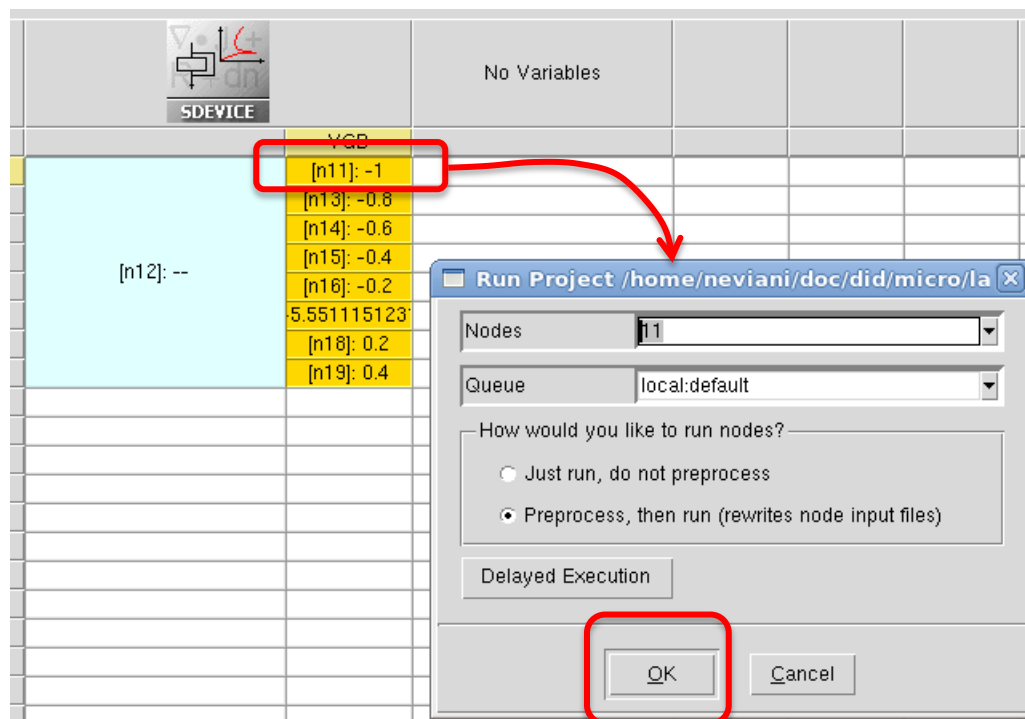
- ❑ Assign the new command file to SDEVICE
  - right-click on the SDEVICE icon → Properties...
  - in the dialog box, select the Input Files tab
  - in the Master File column change the name of the command file to MOScap\_ac.cmd, then click OK





# Tutorial #3: ac simulation

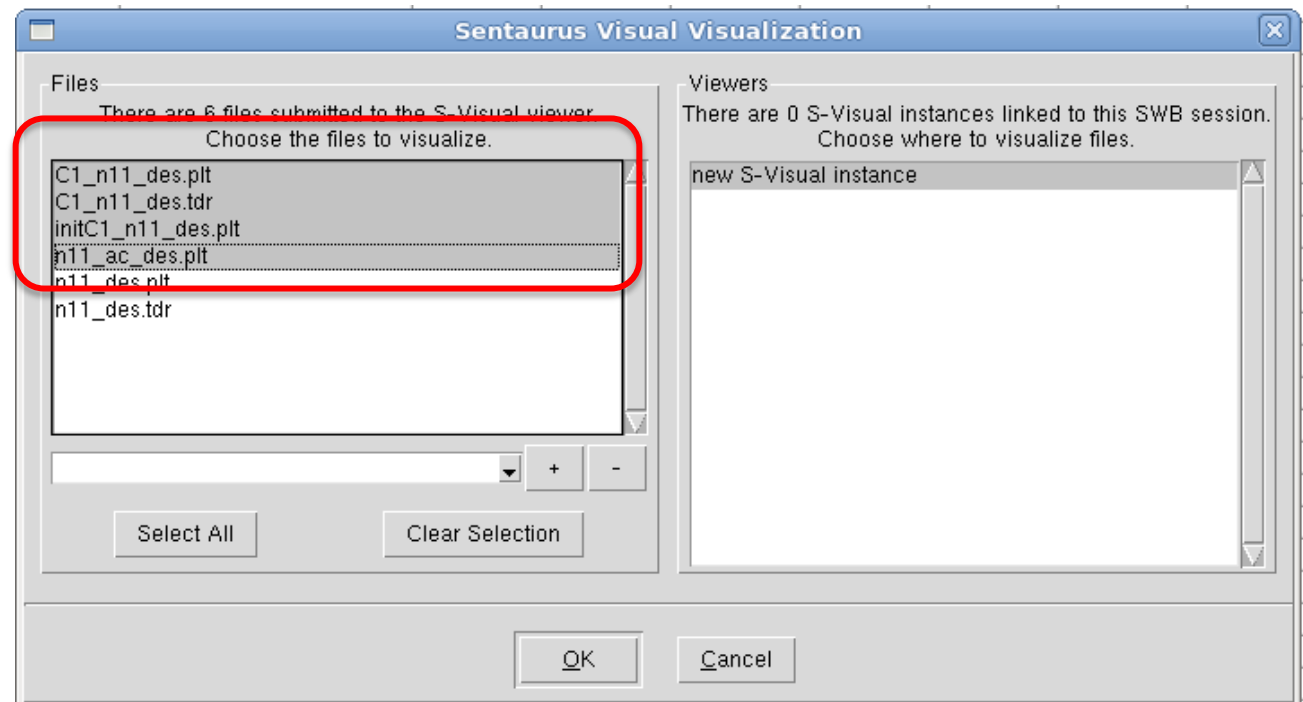
- Run the ac simulation by right-clicking on one of the VGB nodes (e.g. the one corresponding to  $V_{GB} = -1V$ ) → Run... → OK



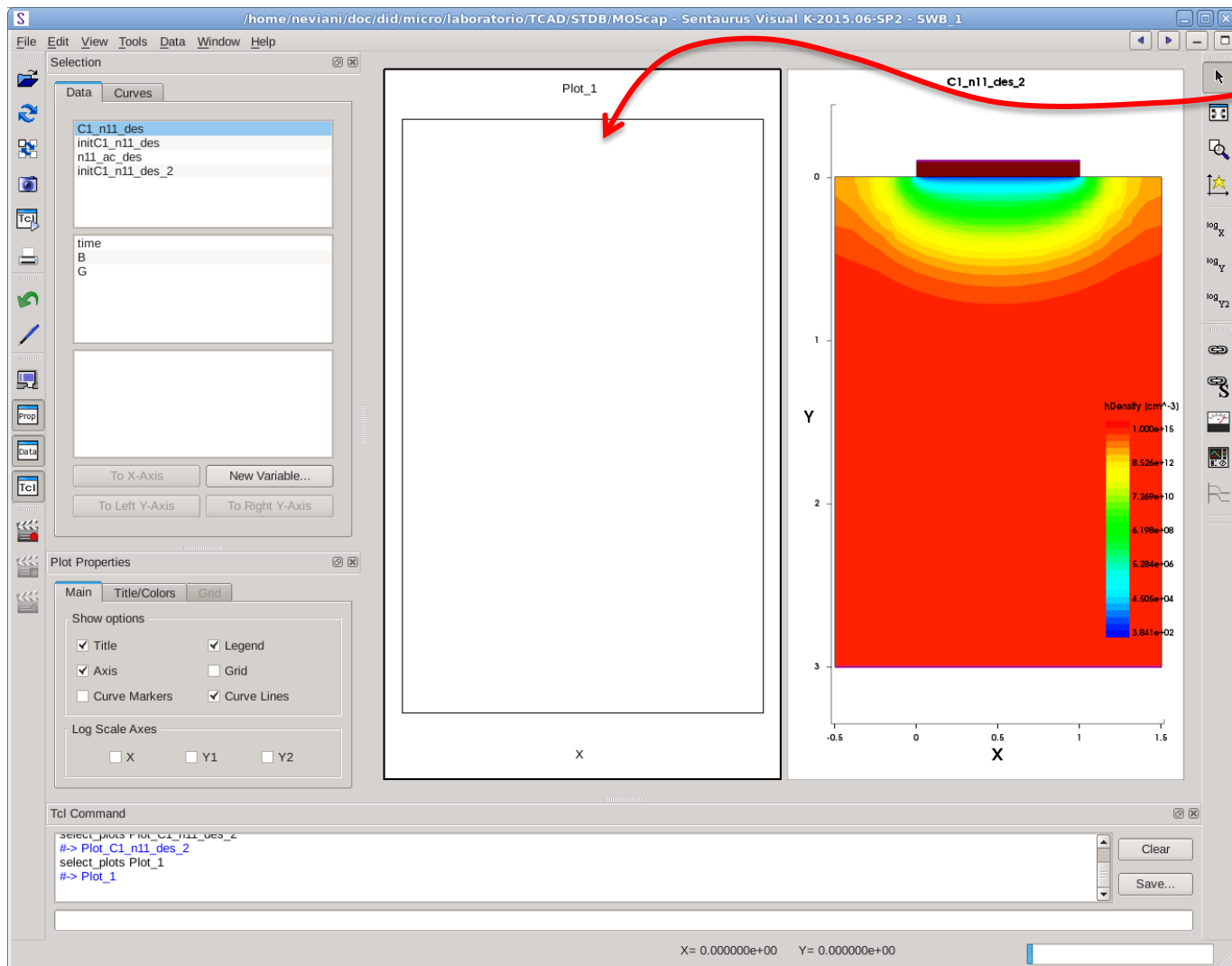
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- ❑ To post-process the simulation results, open SVISUAL by right-clicking on the simulation node → Visualize → Sentaurus Visual (Select File...)

select the output  
files of the ac  
simulation and click  
OK



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click on the Plot\_1 window

the right panel changes to the one shown here

click on  $n11\_ac\_des$  data set (the number may be different from 11)